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10807873 - GAU: 1792

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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> ( Not for submission under 37 CFR 1.99)	Application Number		10807873	
	Filing Date		2005-09-09	
	First Named Inventor	Stasiak et al		
	Art Unit			
	Examiner Name			
	Attorney Docket Number		200309781-1	

#### U.S.PATENTS

Examiner Initial*	Cite No	Patent Number	Kind Code <sup>1</sup>	Issue Date	Name of Patentee or Applicant of cited Document	Pages,Columns,Lines where Relevant Passages or Relevant Figures Appear
	1	5948621	A	1999-09-07	Turner et al	
	2	5776748	A	1998-07-07	Singhvi	

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#### U.S.PATENT APPLICATION PUBLICATIONS

Examiner Initial*	Cite No	Publication Number	Kind Code <sup>1</sup>	Publication Date	Name of Patentee or Applicant of cited Document	Pages,Columns,Lines where Relevant Passages or Relevant Figures Appear
	1	20030054342	A1	2003-03-20	Star et al	
	2	20020119251	A1	2002-08-29	Chen et al	
	3	20030032046	A1	2003-02-13	Duffy et al	
	4	20050118338	A1	2005-06-02	Steve et al	

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#### FOREIGN PATENT DOCUMENTS

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	1	1 484 644	EP	A	2004-12-08	Hewlett Packard		<input type="checkbox"/>
	2	2004/092836	WO	A	2004-10-28	Drain		<input type="checkbox"/>

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	1	Chou, S. et al "Imprint Lithography with Sub-10 nm Feature Size and High Throughput", Microelectronic Engineering, V. 35(1), Feb 1997. pp 237-240	<input type="checkbox"/>
	2	Pfeiffer K et al, "Polymer stamps for nanoimprinting", Microelectronic Engineering, V 61-62, July 2002, pp 393-398	<input type="checkbox"/>
	3	Schift H et al, "Chemical non-patterning using hot embossing lithography", Microelectronic Engineering, V. 61-62, July 2002, pp 423-428	<input type="checkbox"/>
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